ABSTRACT

Disclosed herein are an anisotropically conductive connector, by which positioning, and holding and fixing to a wafer that is an object of inspection can be conducted with ease even when the wafer has a large area of 8 inches or greater in diameter, and the pitch of electrodes to be inspected in integrated circuits formed is small, good conductivity is surely achieved as to all conductive parts for connection, at the same time, insulating property between adjoining conductive parts for connection is surely attained, and moreover the good conductivity is retained over a long period of time even when it is used repeatedly, and applications thereof.

The anisotropically conductive connector of the present invention comprises elastic anisotropically conductive films each having a functional part, in which a plurality of conductive parts for connection containing conductive particles and extending in a thickness-wise direction of the film have been arranged in a state mutually insulated by an insulating part wherein assuming that a thickness of the conductive parts for connection in the functional part of the elastic anisotropically conductive film is T1 and a thickness of the insulating part in the functional part is T2, a ratio (T2/T1) is at least 0.9.